



# ISDEIV2023 Program at a Grance

Date venue	ISDEIV2023 2023/6/28 Wed Venue:Okinawaken Shichoson Jichi Hall		ISDEIV2023 2023/6/29 Thu Venue:Okinawaken Shichoson Jichi Hall			ISDEIV2023 2023/6/30 Fri Venue:Okinawaken Shichoson Jichi Hall	
	JICHIKAIKAN-Hall	Room 201,202,203	JICHIKAIKAN-Hall	Room 201,202,203	Conference Room 7	JICHIKAIKAN-Hall	Conference Room 7
8:00							
	Conference Office opens from 8:30		Conference Office opens from 8:30			Conference Office opens from 8:30	
9:00	Oral Session 6 I(Prof.Kuninaka)(C5) 9:00-10:00 Chair:Michael KURRAT		Oral Session 7 I(Dr.Gortschakow)(B2 ) 9:00-10:40			Oral Session 10 I(Prof.Y.Saito)(B5+C 2) 9:00-10:40	
10:00		Poseter session II (B3+B4+B5) 10:00-11:30	Coffee Break(20min)			Coffee Break(20min)	
11:00			Oral Session 8 I(Dr.Kyritsakis)(B3) 11:00-12:40 Chair:Dirk UHRLANDT			Oral Session 11 I(Dr.H.Saito)(C1) 11:00-12:40 Chair:Zhiyuan LIU	
12:00	Excursion 11:30-18:00		Lunch 12:40-14:00		PISC Meeting III 12:40-14:00	Closing Session 12:40-13:00	
13:00							
14:00			Poster Session III (C1-C5, D) 14:00-15:30				
15:00			Coffee Break(30min)		Award Committee III 15:30-16:00		
16:00			Japan Prize Session & Oral Session 9 (B3) 15:45-17:25 Chair:René P.P. SMEETS				
17:00							
18:00							
19:00	Banquet 18:00-21:00						
20:00							
21:00							

Invited talk: 25min.

Oral presentation:15min. including discussion and change of presentation

A1. Vacuum breakdown and pre-breakdown phenomena

A2. Surface discharges and flashover phenomena

B1. Switching in vacuum and related phenomena

B2. Interaction of vacuum arcs with magnetic fields

B3. Vacuum arc physics

B4. Computer modeling and computer aided design

B5. Pulsed power physics and technology

C1. Vacuum interrupters and their applications

C2. Surface science and modification and related technologies

C3. Electron, ion, neutron, X-ray and other beam and light sources

C4. Accelerator and fusion reactor related issues

C5. Space related technologies

C6. Vacuum microelectronics and their applications

D.OTHERS